AMENDMENTS TO THE SPECIFICATION

Please replace the first full paragraph on page 7, with the following rewritten paragraph:

--As illustrated in Figure 3a, the X, Y controller 14 further includes a deposition substrate 25 movably and removably affixed thereto. The deposition substrate 25 is the surface upon which the present invention deposits the material. The deposition substrate 25 is moved by the X, Y controller 14 into a position underneath the Z controller 16 so that ~~that~~ the deposition probe 12 can be lowered and the deposition material deposited. The deposition substrate 25 may be affixed to the X, Y controller 14 utilizing snaps, clips, raised contours, or by other methods known to those skilled in the art. The details of how the arrayer 10 deposits the material is better understood after an explanation of each of the portions of the present embodiment. In still further embodiments, one controller may control the movement of the deposition probe 12 in the X, Y, and Z directions.--

Please replace the second paragraph under the heading "Base 24" on page 8, with the following rewritten paragraph:

--One commercially available optical plate 24 that may be well suited for use in the present invention arrayer ~~12~~ 10 may be available from Newport Corp., P.O. Box 19607, Irvine CA 92623-9607 as product number SA12. The plate may have ¼ inch holes drilled on one inch centers. Steel posts 26 well suited for the present invention may also be commercially available from the same manufacturer as product number SP12.--

Please replace the first paragraph under the heading "Controller 14" on page 8, with the following rewritten paragraph:

--With reference to Figures 2 and 3a, the X, Y controller 14 of the present invention will be herein described. As illustrated in Figures 2 and 3a, the ~~X, Y, control 14~~ X, Y controller 14 may be operably attached to the base 24. The X, Y controller 14 should be capable of microfine and repeatable movement so that the attached deposition substrate 25 can be precisely positioned in a repeatable manner underneath the deposition probe 12. The operative end of the X, Y controller 14, as illustrated in Figure 2, may be positioned in such a manner that the X, Y controller 14 will move the deposition substrate 25 underneath the deposition probe 12 with micron precision and will also be able to move the deposition

substrate 25 out of the way to allow the X, Y translation stage 18 to move the loading substrate 27 under the deposition probe 12.--